

## WEST Search History

Hide Items

Restore

Clear

Cancel

DATE: Tuesday, January 29, 2008

Hide?	Set Name	Query	Hit Count
<i>DB=USPT; PLUR=YES; OP=ADJ</i>			
<input type="checkbox"/>	L35	L32 and @pd > 20080129	0
<input type="checkbox"/>	L34	US-7070915-B2.did.	1
<input type="checkbox"/>	L33	US-7070915-B2.did.	1
<i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>			
<input type="checkbox"/>	L32	L29 same surfactant	0
<input type="checkbox"/>	L31	L27 same (cleaning or removing)	0
<input type="checkbox"/>	L30	L27 same L21	0
<input type="checkbox"/>	L29	L16 same L20	0
<input type="checkbox"/>	L28	L16 same surfactant	0
<input type="checkbox"/>	L27	L16 with surfactant	0
<i>DB=PGPB; PLUR=YES; OP=ADJ</i>			
<input type="checkbox"/>	L26	US-20050205108-A1.did.	1
<input type="checkbox"/>	L25	US-20050205108-A1.did.	1
<i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>			
<input type="checkbox"/>	L24	L21 with L19 with L18	1
<input type="checkbox"/>	L23	fluid adj10 surfactant	8358
<input type="checkbox"/>	L22	wafer or semiconductor	2110371
<input type="checkbox"/>	L21	lens or (optical lens)	872335
<input type="checkbox"/>	L20	cleaning or rinsing	1012418
<input type="checkbox"/>	L19	L16 or (ILS)	2104915
<input type="checkbox"/>	L18	immersion lithography system	294
<i>DB=USPT; PLUR=YES; OP=ADJ</i>			
<input type="checkbox"/>	L17	US-7070915-B2.did.	1
<input type="checkbox"/>	L16	US-7070915-B2.did.	1
<i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>			
<input type="checkbox"/>	L15	L14 same surfactant	1
<input type="checkbox"/>	L14	L12 same (cleaning or removing)	21
<input type="checkbox"/>	L13	L12 same l6	2
<input type="checkbox"/>	L12	l1 same l5	189
<input type="checkbox"/>	L11	l1 same surfactant	6
<input type="checkbox"/>	L10	l1 with surfactant	2

*DB=PGPB; PLUR=YES; OP=ADJ*

<input type="checkbox"/>	L9	US-20050205108-A1.did.	1
<input type="checkbox"/>	L8	US-20050205108-A1.did.	1

*DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ*

<input type="checkbox"/>	L7	L6 with L4 with L3	4
<input type="checkbox"/>	L6	fluid adj10 surfactant	8358
<input type="checkbox"/>	L5	wafer or semiconductor	2110371
<input type="checkbox"/>	L4	lens or (optical lens)	872335
<input type="checkbox"/>	L3	cleaning or rinsing	1012418
<input type="checkbox"/>	L2	L1 or (ILS)	2105161
<input type="checkbox"/>	L1	immersion lithography system	294

END OF SEARCH HISTORY